## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

## IAP20 Rec'd PCT/PTO 09 JUN 2006

Elisabeth DELEVOYE

Application No.: New U.S. National Stage of PCT/FR2004/003203

Filed: June 9, 2006 Docket No.: 128180

For: MICRO-MACHINED VIBRATING STRUCTURE AND ASSOCIATED MICRO-

**GYROSCOPE** 

## **INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.

Respectfully submitted,

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WPB:JOC/nxy

Date: June 9, 2006

OLIFF & BERRIDGE, PLC P.O. Box 19928 Alexandria, Virginia 22320 Telephone: (703) 836-6400 DEPOSIT ACCOUNT USE AUTHORIZATION

Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461

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Sheet 1 of 1

Form PTO-1449 (REV. 1/06) INFORMA		US Dept. of Commerce PATENT & TRADEMARK OFFICE TION DISCLOSURE STATEMENT		ATTY D 128180	OCKET NO.	1	0/5	APPLICAT	Ational A
(Use several sheets if necessary)				APPLICANT Elisabeth DELEVOYE					
				FILING DATE June 9, 2006					
U.S. PATENT DOCUMENTS									
Examiner Initials	Cite No.	Document Number	Date		Name				
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FOREIGN PATENT DOCUMENTS									
Examiner Initials	Cite No.	Document Number	Da	te	(	Country		With English Abstract	With English Translation
	1.	EP 0 904 522 A	03/31/1999		EUROPE				
	2.	WO 02/057728 A	07/25/2002		WIPO				
	3.	EP 1 126 242 A	08/22/2001		EUROPE				
OTHER DOCUMENTS									
Examiner Initials									
	4.	MAENAKA et al.; "A study of silicon angular rate sensors using anisotropic etching technology"; Sensors and Actuators;							
	Vol. A43; No. 1/3; May 1, 1994; pgs. 72-77.								
EXAMINER							DATE CONSIDERED		
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.									

Date: June 9, 2006